

	L #	Hits	Search Text	DBs	Time Stamp
1	L1	8146	(427/2.1-2.31,488-491,535-539,562-564,569-579).CCLS.	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/24 15:09
2	L2	3975	((plasma .(glow electric corona)adj discharg\$4)with(atmospheric adj pressure "1 atm" "1 atmosphere" "736 torr" "736 mmHg" "736 mm Hg" atm))	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/24 15:15
3	L3	300	1 and 2	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/24 15:09
4	L4	2211	(427/2.1-2.31).CCLS.	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/24 15:09

10/017,193

	L #	Hits	Search Text	DBs	Time Stamp
5	L5	45	3 and(cell protein peptide amino adj acid P15 "P-15" cadherin) <i>missed nucleic acids</i>	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/2 4 15:15
6	L6	1197	4 and(cell protein peptide amino adj acid P15 "P-15" cadherin)	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/2 4 15:16
7	L7	681	4 and(plasma (glow electric corona)adj discharg\$4)	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/2 4 15:16
8	L8	519	7 and(cell protein peptide amino adj acid P15 "P-15" cadherin)	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/2 4 15:17

	L #	Hits	Search Text	DBs	Time Stamp
9	L9	4	3 and (laminin fibronectin collagr vitronectin tenascin fibrinogen thrombospondin osteopontin von adj willibrand adj factor sialoprotein)	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/2 4 15:20
10	L10	148	7 and (laminin fibronectin collagr vitronectin tenascin fibrinogen thrombospondin osteopontin von adj willibrand adj factor sialoprotein)	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/2 4 15:21
11	L11	147	7 and (collagen)	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/2 4 15:21
12	L12	4	3 and (collagen)	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/2 4 15:22

	L #	Hits	Search Text	DBs	Time Stamp
13	L13	3	12 and 9	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/2 4 15:22
14	L14	5	12 or 9	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/2 4 15:24
15	L15	211	10 or 11	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/2 4 15:23
16	L16	84	10 and 11	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/2 4 15:23

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	L #	Hits	Search Text	DBs	Time Stamp
17	L17	45	12 or 9 or 5	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/24 15:24
18	L18	5	12 or 9 and 5	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/24 15:24
19	L19	40	17 not 18	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2003/06/24 15:25

20 L20 (6) 19 + (PTFE or polytetrafluoroethylene or ----- )  
 21 (34) 19 not 20

L18

6

these

11/12/98

pull  
103 types

pull

\*

	Document ID	Issue Date	Title	Current OR	Inventor
1	US 20030113478 A1	20030619	Surface coating method and coated device	427/535	Dang, Mai Huong et al.
2	US 20030008397 A1	20030109	Coupled peptide s	435/402	Beumer, Gerrit Jan et al.
	US 6131580 A	20001017	Templated imprint ed materials by RF plasma deposit ion	128/898	Ratner, Buddy D. et al.
4	US 5455108 A	19951003	Coated polymer ic fabric having reduced adsorpt ion of protein	442/126	Quincy, III, Roger B. et al.
5	US 5364662 A	19941115	Surface treatme nt of silicon e rubber	427/536	Domenic o, Edward D. et al.

Ab Silicon Rubber - plasma treated in  $H_2$  or  $N_2$  or  $He$ ,  $Ne$ ,  $Ar$  (G-free)  
graph covalent attachment, ex- bioactive

\* (D) A reactor ... react to 250-300 mtorr, then bring back to 1 atm by intro of plasma gas

L19

7

	Document ID	Issue Date	Title	Current OR	Inventor
1	US 2003008 2412 A1	20030501	Method for forming thin film, article having thin film, optical film, dielectric coated electrode, and plasma discharge processor	428/697	Fukuda, Kazuhir o et al.
<del>2</del>	US 2003007 2891 A1	20030417	Thin film forming method, optical film, polarizing film and image display method	427/569	Murakami, Takashi et al.
<del>3</del>	US 2002017 6946 A1	20021128	Porous plasma treated sheet material	427/569	O'Brien, Jeffrey J.
<del>4</del>	US 2002017 2779 A1	20021121	Treating cavitated polymeric films with plasma at atmospheric pressure	427/569	O'Brien, Jeffrey J.

	Document ID	Issue Date	Title	Current OR	Inventor
<del>5</del>	US 2002016 8466 A1	2002111 4	System and process for solid-state deposition and consolidation of high velocity powder particles using thermal plastic deformation	427/180	Tapphorn, Ralph M. et al.
L20 6	US 2002012 2896 A1	2002090 5	Capillary discharge plasma apparatus and method for surface treatment using the same	427/569	Kim, Steven et al.
L20 7	US 2002010 6500 A1	2002080 8	Plasma curing process for porous low-k materials	428/304 .4	Albano, Ralph et al.



	Document ID	Issue Date	Title	Current OR	Inventor
8	US 6583064 B2	20030624	Low contamination high density plasma etch chambers and methods for making the same	438/710	Wicker, Thomas E. et al.
9	US 6548123 B1	20030415	Method for coating a plastic container with vacuum vapor deposition	427/566	Plester, George et al.
10	US 6472076 B1	20021029	Deposition of organosilsesquioxane films	428/447	Hacker, Nigel P.

	Document ID	Issue Date	Title	Current OR	Inventor
<del>11</del>	US 6417071 B2	20020709	Sub-atmospheric pressure thermal chemical vapor deposition (SACVD) trench isolation method with attenuated surface sensitivity	438/424	Jang, Syun-Ming
<del>12</del>	US 6403490 B1	20020611	Method of producing a plasma by capacitive-type discharges with a multiple barrier, and apparatus for implementing such a method	438/710	Lagarde, Thierry et al.

	Document ID	Issue Date	Title	Current OR	Inventor
120 13	US 6159531 A	20001212	Coating having biological activity and medical implant having surface carrying the same and method	427/2.24	Dang, Mai Huong et al.
14	US 6130397 A	20001010	Thermal plasma annealing system, and annealing process	219/121.37	Arai, Michio
15	US 5993917 A	19991130	Method and apparatus for improving wettability of foam	427/536	Pan, Alfred I-Tsung et al.
16	US 5968611 A	19991019	Silicon nitrogen-based films and method of making the same	427/579	Kaloyeros, Alain E. et al.

L20

	Document ID	Issue Date	Title	Current OR	Inventor
17	US 5843789 A	19981201	Method of analysis of genomic biopolymer and porous materials for genomic analyses	436/164	Nomura, Hiroshi et al.
18	<i>Vac cell</i> US 5616368 A	19970401	Field emission devices employing activated diamond particle emitter s and methods for making same	427/535	Jin, Sungho et al.
19	<i>open cell sensor</i> US 5587207 A	19961224	Arc assisted CVD coating and sintering method	427/571	Gorokhovsky, Vladimir I.

	Document ID	Issue Date	Title	Current OR	Inventor
20	US 5547716 A	19960820	Laser absorption wave deposition process and apparatus	427/577	Thaler, Stephen L.
21	US 5510151 A <i>Solar</i>	19960423	Continuous film-forming process using microwave energy in a moving substrate web functioning as a substrate and plasma generating space	427/509	Matsuyama, Jinsho et al.
22	US 5470784 A <i>Solar</i>	19951128	Method of forming semiconducting materials and barrier s using a multiple chamber arrangement	438/61	Coleman, John H.

	Document ID	Issue Date	Title	Current OR	Inventor
23	US 5441765 A <i>photo voltaic</i>	19950815	Method of forming Si-O containing coatings	427/228	Ballance, David S. et al.
24	US 5409743 A	19950425	PECVD process for forming BPSG with low flow temperature	427/579	Bouffard, Mark D. et al.
25	US 5366770 A	19941122	Aerosol-plasma deposition of films for electronic cells	505/477	Wang, Xingwu
26	US 5324553 A	19940628	Method for the improved microwave deposition of thin films	427/571	Ovshinsky, Stanford R. et al.
27	US 5260105 A	19931109	Aerosol-plasma deposition of films for electrochemical cells	427/576	Wang, Xingwu

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(38) Mohs table  
plan. process of materials

(39) of separator of low  
dis. reaction

	Document ID	Issue Date	Title	Current OR	Inventor
28	US 5192717 A	19930309	Process for the formation of a polycrystalline semiconductor film by microwave plasma chemical vapor deposition method	438/479	Kawakami, Soichiro et al.
29	US 5143748 A	19920901	Timber surface improving treatment process	427/569	Ishikawa, Hiroyuki et al.
30	US 5017308 A	19910521	Silicon thin film and method of producing the same	252/501.1	Iijima, Shigeru et al.

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	Document ID	Issue Date	Title	Current OR	Inventor
31	US 4792460 A	19881220	Method for production of polysilanes and polygermanes, and deposition of hydrogenated amorphous silicon, alloys thereof, or hydrogenated amorphous germanium	427/563	Chu, Ting L. et al.
32	US 4743258 A	19880510	Polymer materials for vascular prostheses	623/1.49	Ikada, Yoshito et al.
33	US 4537795 A	19850827	Method for introducing sweep gases into a glow discharge deposition apparatus	427/569	Nath, Prem et al.



17

	Document ID	Issue Date	Title	Current OR	Inventor
<del>34</del>	US 4527007 A	19850702	Process for forming passivation film on photoelectric conversion device and the device produced thereby	136/256	Fuse, Mario
<del>35</del>	US 4485121 A	19841127	Method for producing a fluorine-containing amorphous semiconductor	438/483	Matsumura, Hideki
<del>36</del>	US 4481229 A	19841106	Method for growing silicon-including film by employing plasma deposition	427/571	Suzuki, Keizo et al.
<del>37</del>	US 4439463 A	19840327	Plasma assisted deposition system	427/563	Miller, Stephen C.

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	Document ID	Issue Date	Title	Current OR	Inventor
38	US 4382099 A	19830503	Dopant predeposition from high pressure plasma source	438/57	Legge, Ronald N. et al.
39	US 4226898 A	19801007	Amorphous semiconductors equivalent to crystal line semiconductors produced by a glow discharge process	438/483	Ovshinsky, Stanford R. et al.
40	US 4226897 A	19801007	Method of forming semiconducting materials and barriers	438/96	Coleman, John H.

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(A10) improved porous filter

	Document ID	Issue Date	Title	Current OR	Inventor
5	US 5843789 A	19981201	Method of analysis of genomic biopolymer and porous materials for genomic analysis	436/164	Nomura, Hiroshi et al.
6	US 4743258 A	19880510	Polymer materials for vascular prostheses	623/1.49	Ikada, Yoshito et al.

(B2) nucleic acid filter

(D8) method of sample formation

(P16) PTFE gas plasma at 100 mtorr

← aqueduct to lake

★

(B3) Vascular prosthesis for porous PTFE ...

(B8) It is oxygen - little protein adsorption

(B15) A wide range of PTFE

(D6) A commercial corona discharge at 1 atm

(P11) ... prosthesis measured

(L2e)

	Document ID	Issue Date	Title	Current OR	Inventor
1	US 20030072891 A1 <i>L. X. all</i> <i>PTFE electrical conduct</i>	20030417	Thin film forming method, optical film, polarizing film and image display method	427/569	Murakami, Takashi et al.
2	US 20020122896 A1 <i>[0002] present Im-planer at latum</i> <i>[0005] PTFE not in present</i>	20020905	Capillary discharge plasma apparatus and method for surface treatment using the same	427/569	Kim, Steven et al.
3	US 20020106500 A1 <i>[0019] sub list... PTFE</i> <i>[0020] ... photo voltaic cells</i>	20020808	Plasma curing process for porous low-k materials	428/304.4	Albano, Ralph et al.
4	US 6159531 A <i>pull</i> <i>exactly 1 yr</i>	20001212	Coating having biological activity and medical implant having surface carrying the same and method	427/2.24	Dang, Mai Huong et al.

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